

ABSTRACT OF THE DISCLOSURE

The semiconductor device comprises: insulating films 40, 42 formed over a substrate 10; an interconnection 58 buried in at least a surface side of the insulating films 40, 42; insulating films 60, 62 formed on the insulating film 42 and including a hole-shaped via-hole 60 and a groove-shaped via-hole 66a having a pattern bent at a right angle; and buried conductors 70, 72a buried in the hole-shaped via-hole 60 and the groove-shaped via-hole 66a, wherein the groove-shaped via-hole 66a is formed to have a width which is smaller than a width of the hole-shaped via-hole 66. Whereby, the defective filling of the buried conductor is prevented, and the cracking of the inter-layer insulating film can be prevented. Steps on the conductor plug can be reduced, so that the step cannot be influential on the upper interconnection layers and insulating layers. Accordingly, defective contact with the upper interconnection layer and the problems taking place in forming films can be prevented, and resultantly the semiconductor device can have high water resistance and high interconnection reliability.